EE506: Optical interferometry and laser metrology
To be offered Fall 2021

Course Outline

Instructor: Mario Marconi
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Prerequisite[s]: EE342, EE441 or equivalent basic laser course (optional).
Course description: The subject of the course will be focused in describing and analyzing
different schemes of interferometers and interferometric measurements. The course will
review basic concepts related with light interference such coherence, laser sources. We will
emphasize applications of interferometers to high resolution metrology, microscopy, high
resolution optical sensors (fiber optics), etc. A significant component of the course will be
focus on reading and critical discussion of research papers using the topics reviewed in
class.

Textbooks: Notes provided by instructor. "Optical Interferometry", P. Hariharan.

Syllabus:
Week 1: Interferometry: Basis and developments
Week 2-3 Two beam interference (Wavefront division, Amplitude division)
Week 4-5 Coherence (Quasi monochromatic light, Mutual coherence function,
Temporal coherence, Spatial coherence)
Week 6-7 Multiple beam interference
Week 8-9 Lasers (Laser modes, Single frequency operation, Frequency
stabilization)
Week 10 Electronic phase measurements
Week 11 Measurements techniques, sensors
Week 12 Optical testing
Week 13 Interference microscopy, Interference spectroscopy, Interferometric
sensors
Week 14 Break
Week 15-16 Review

Grading: Students will complete 3 series of problems (25% each) that will be assigned
during the semester. The last assignment (25%) will consist of answering a set of questions
on a research paper that will be assigned before the Fall break. There is no in class
evaluation, all assignments will be completed at home.